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CONFIRMATION NO. 7930

SERIAL NUMBER	FILING or 371(c) DATE	CLASS	GROUP ART UNIT	ATTORNEY DOCKET NO.
10/018,188	12/18/2001	451	3724	511.40998X00
RULE				
APPLICANTS Naoyuki Koyama, Ibaraki, JAPAN; Kouji Haga, Ibaraki, JAPAN; Masato Yoshida, Ibaraki, JAPAN; Keizou Hirai, Ibaraki, JAPAN; Toronosuke Ashizawa, Ibaraki, JAPAN; Youiti Machii, Ibaraki, JAPAN;				
** CONTINUING DATA ***** This application is a 371 of PCT/JP00/03891 06/15/2000				
** FOREIGN APPLICATIONS ***** JAPAN 172821/1999 06/18/1999 JAPAN 204842/1999 07/19/1999 JAPAN 332221/1999 11/24/1999				
** IF REQUIRED, FOREIGN FILING LICENSE GRANTED **				
Foreign Priority claimed <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No 35 USC 119(a-d) conditions met <input checked="" type="checkbox"/> Yes <input type="checkbox"/> No Verified and Acknowledged <u>/TIMOTHY V ELEY/</u> Examiner's Signature	<input type="checkbox"/> Met after Allowance <u>tve</u> Initials	STATE OR COUNTRY JAPAN	SHEETS DRAWINGS	TOTAL CLAIMS 12
			INDEPENDENT CLAIMS	2
ADDRESS Antonelli Terry Stout & Kraus Suite 1800 1300 North Seventeenth Street Arlington, VA 22209 UNITED STATES				
TITLE Abrasive compound for cmp, method for polishing substrate and method for manufacturing semiconductor device using the same, and additive for cmp abrasive compound				
FILING FEE RECEIVED 1726	FEES: Authority has been given in Paper No. _____ to charge/credit DEPOSIT ACCOUNT No. _____ for following:		<input type="checkbox"/> All Fees <input type="checkbox"/> 1.16 Fees (Filing) <input type="checkbox"/> 1.17 Fees (Processing Ext. of time) <input type="checkbox"/> 1.18 Fees (Issue) <input type="checkbox"/> Other _____ <input type="checkbox"/> Credit	